EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	5935	29/602.1,605,606.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:44
S2	6718	336/65,83,200,206-208,220-223, 232.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:40
S3	708	257/531.ccls.	US-PGPUB; USPAT;	OR	ON	2006/07/18 09:40
S4	6239	438/238,381,106,107.ccls.	EPO; JPO US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:41
S5	7	LIANG-MORRIS-p-f.in. or CHUANG-SWAY.in. or FAN-FRANK-k-c.in. or KAO-CHEN-chung.in.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:43
S6	3	S5 and (microcoil or (micro adj coil))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:00
S7	8308	29/602.1,605,606,846.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 09:44
S8	6	("5448822" "5576680" "5852866" "5877924" "6015742" "6441715").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2006/07/18 09:45
S9	10	S1 and (microcoil or (micro adj coil))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18-10:01
S11	36	S2 and (microcoil or (micro adj coil))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:01
S12	7	S9 and S11	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:04
S13	1307	inject\$3 with (conduct\$3 or metal\$3) with (coil or (coil near winding))	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07
S14	1733	216/39,41.ccls.	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07
S15	164	photolithography with photoresist with coil	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07

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S16	4	S13 and S15	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:07
S17	1	(US-6600404-\$).did.	USPAT	OR .	ON	2006/07/18 10:14
S18	3	S17 and "fig." S6	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15
S19	. 0	S17 and FIG	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15
S20	0	S17 and fig	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15
S21	1	S17 and photoresist	US-PGPUB; USPAT; EPO; JPO	OR	ON	2006/07/18 10:15



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IEEE JNL	IEEE Journal or Magazine	view selected items Select All Deselect All	
IEE JNL	IEE Journal or Magazine		
IEEE CNF	IEEE Conference Proceeding	1. Thermomechanical head performance Pust, L.; Rea, C.J.T.; Gangopadhyay, S.;	
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